

N POLITECNICO DI MILANO

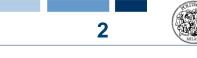


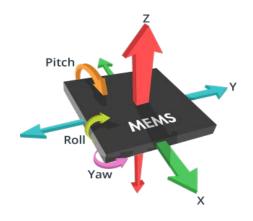


Department of Civil and Environmental Engineering

www.mems.polimi.it

www.mems3d.polimi.it





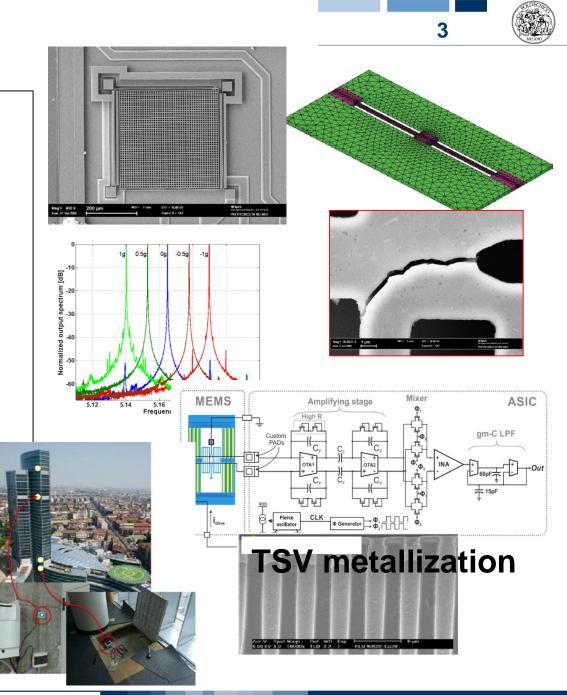
MEMS @ Polimi

- Research on MEMS since 2002
- Strict cooperation with STMicroelectronics
- Industrial, Regional, National and EU projects.
- Teaching at master and PhD levels in Materials Eng. & Nanotechnology and Electronics study courses

MEMS @ Polimi

Research activities

- Theory
- Modelling and simulation
- Design
- Characterization and reliability
- Devices
- Interface electronics
- Instrumentation for MEMS
- Fabrication processes
- Additive manufacturing
- Applications



Alberto Corigliano - Micro Electro Mechanical Systems (MEMS)

4

MEMS @ Polimi

• Polimi network on MEMS:

Dep. Civil and Environmental Eng. (DICA)

Dep. Electronics, Information T. and Bio-Eng. (DEIB)

Dep. Chemistry, Materials and Chemical Eng. (DCMIC)

Dep. of Mechanical Eng. (MEC),

+ Dep. of Mathematics, Dep. of Aerospace Sciences

• MEMS&3D lab. www.mems3d.polimi.it DICA, DEIB, DCMIC,

MEC, on microsystems and additive manufacturing (3D + ink-jet printing at micro scale)



• Parallel initiative: Polifab, clean room for micro-fabrication

Civil and Environmental Engineering for MEMS

MEMS modelling and design group

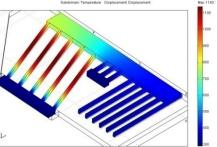
Raffaele Ardito, Claudia Comi, Alberto Corigliano, Attilio Frangi, Aldo Ghisi, Stefano Mariani

Structural and materials mechanics at micro (μ) and nano (n) scale

www.mems.polimi.it

Dip. Ingegneria Civile e Ambientale

SPRINGS FOR HEAT DISSIPATION BESIPATION BEAMS HEATED BEAMS HEATED BEAMS HEATED BEAMS HEATED DISSIPATION DISSIPATIO



5

Contact:

Alberto Corigliano

tel. +390223994244, Fax +390223994330 - alberto.corigliano@polimi.it

Alberto Corigliano - Micro Electro Mechanical Systems (MEMS)



MEMS research activities

Characterization and reliability

- Mechanical characterization at the micro scale
- Fracture-fatigue
- Accidental impacts
- Dissipative phenomena: fluid damping, solid damping, anchor losses
- Stiction (spontaneous adhesion)

Device design

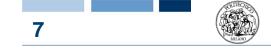
- Electro-thermomechanical actuators
- Capacitive
 accelerometers
- Resonant accelerometers
- Electrostatic
 micropump
- Resonant gyroscope + accelerometers
- Magnetometers
- Piezoelectric devices
- Threshold shock sensors
- Energy harvesters
- Resonators

Modelling & Simulation

6

- Multi-physics
- Fracture initiation and propagation in polycrystalline materials
- Domain Decomposition methods
- Model Order Reduction methods + Domain Decomposition

Research subjects which can be related to MS theses



- 1. MEMS reliability
- 2. MEMS modelling & simulation
- 3. Theoretical study and numerical modelling of damping
- 4. Resonators
- 5. Micro-mirrors
- 6. Micro-gyroscopes
- 7. Piezoelectric Energy harvesters
- 8. Piezo Micro Ultrasound Transducers PMUT
- 9. Technology and fabrication process related activities
- 10. Additive manufacturing applied to MEMS

Alberto Corigliano - Micro Electro Mechanical Systems (MEMS)

Most of the activities in strict cooperation with STMicroelectronics, other groups of Polimi and international groups at: MIT, UC Davis, Northwestern University, EU partners in EU funded projects







1. MEMS reliability



Objective: To deeply investigate issues related to micromechanical components reliability (mechanical effects, rupture, spontaneous adhesion...)

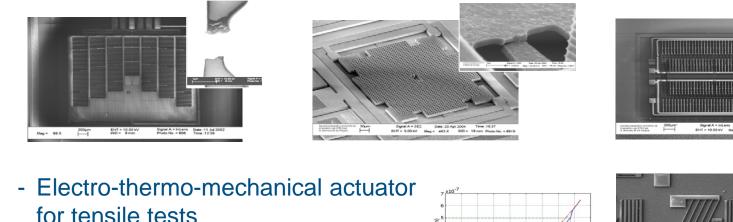
Main achievements:

- 1.1 Experimental mechanical characterization of polysilicon through on-chip test methodology (elastic stiffness, tensile strength, Weibull approach, fracture, fatigue,...)
- 1.2 Experimental set-up for on chip testing with lock-in methodology
- 1.3 Theoretical, experimental and numerical study of spontaneous adhesion phenomena in MEMS (stiction)

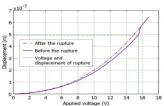
• Collaboration with STM and electronics and material science groups in Polimi

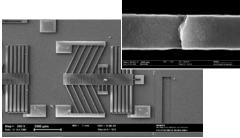
1.1 Reliability - Experimental mechanical 9 characterization of polysilicon through on-chip test methodology (elastic stiffness, tensile strength, fracture, fatigue, Weibull approach...)

- Electrostatic actuators for tensile, bending, fracture and fatigue tests

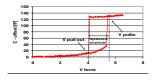


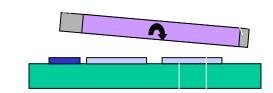


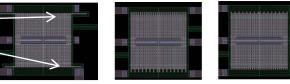




- Test structures for spontaneous adhesion detection



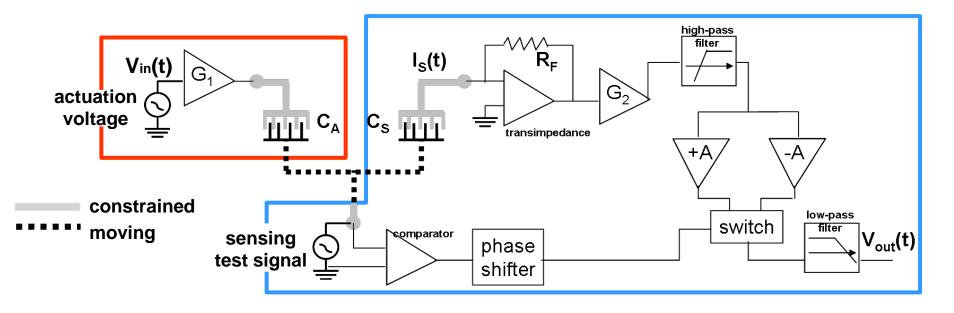




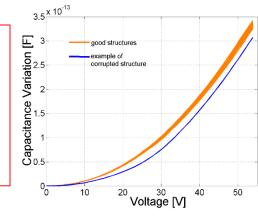


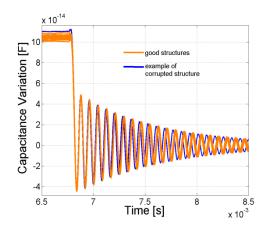


1.2 Reliability - Experimental set-up for on chip testing with lock-in methodology

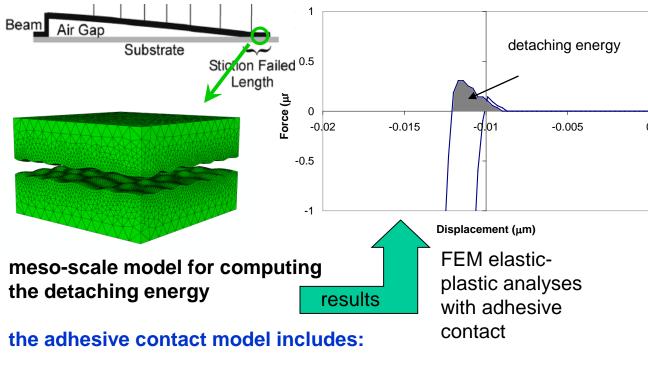


Laboratory set-up for the execution of on-chip testing. Applied to fracture and fatigue tests, resonant accelerometer characterization





1.3 Reliability - Theoretical, experimental and numerical study of spontaneous adhesion phenomena in MEMS (stiction)



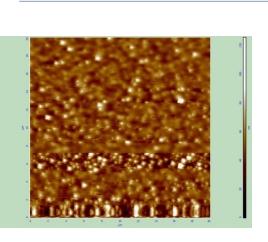
capillary attraction
depends on:
relative humidity
temperature
surface gap
shape of asperities

 "dispersion" forces
 (Van der Waals, Casimir)
 depend on:
 material features

surface gap

surface geometry





11

AFM measurements of surface roughness

Alberto Corigliano - Micro Electro Mechanical Systems (MEMS)

2. MEMS modelling & simulation



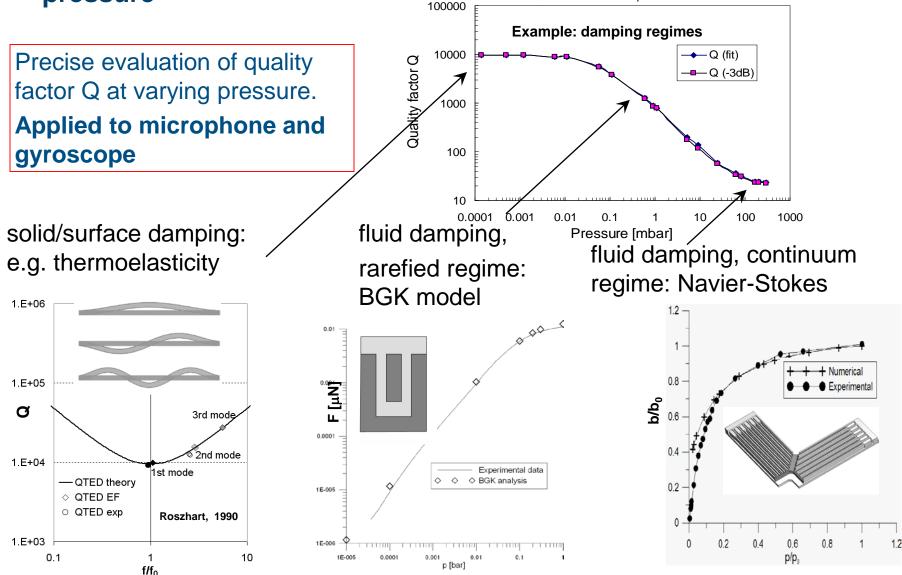
Objective: To perform specific modelling & simulation activities for MEMS

Main achievements:

- 2.1 Numerical modelling and simulation of fluid damping in MEMS at varying pressure
- 2.2 Numerical simulation of electrostatic problems: precise evaluation of capacitance and electrostatic force for complex geometries
- 2.3 Numerical modelling and simulation of accidental drop impacts
- 2.4 Numerical modelling and simulation of 3D fracture processes in polycrystals
- 2.5 Numerical modelling and simulation of multi-physics problems in MEMS
- Collaboration with state of the art international computational mechanics groups

2.1 MEMS modelling - Numerical modelling and simulation of fluid damping in MEMS at varying pressure

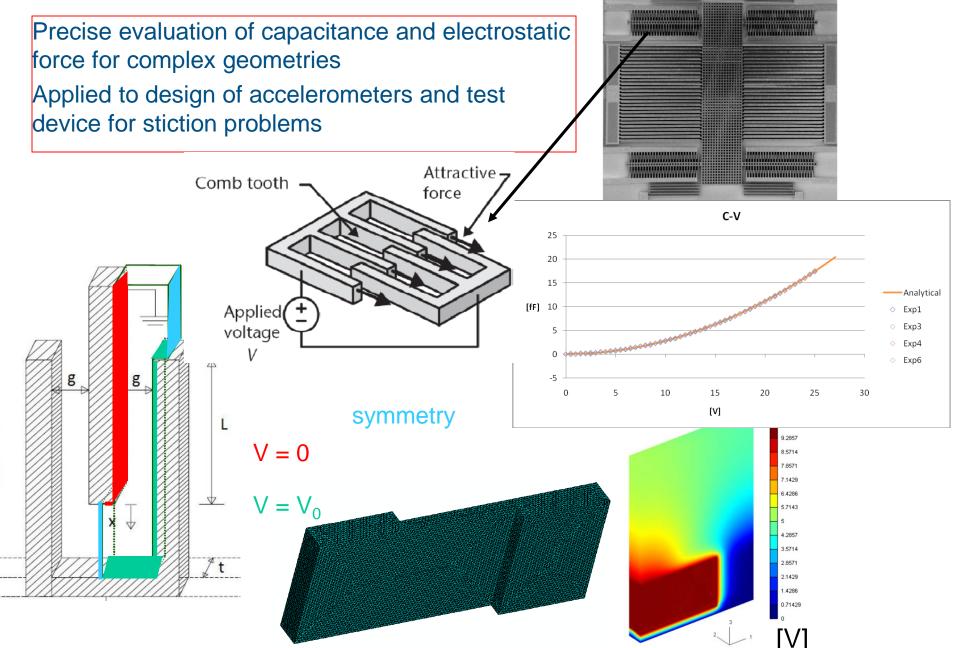




Alberto Corigliano - Micro Electro Mechanical Systems (MEMS)

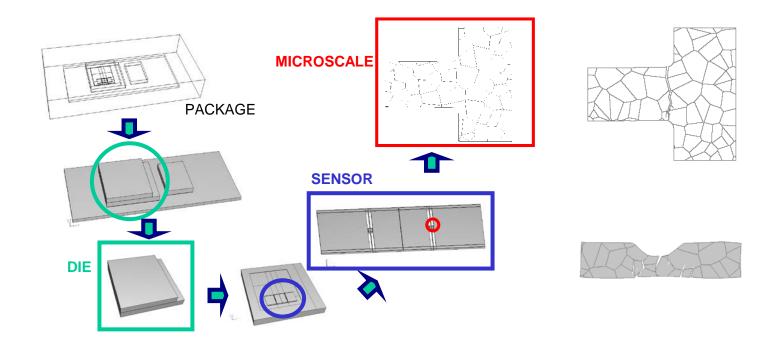
2.2 MEMS modelling - -Numerical simulation of electrostatic problems





2.3 MEMS modelling - Numerical modeling and simulation of accidental drop impacts

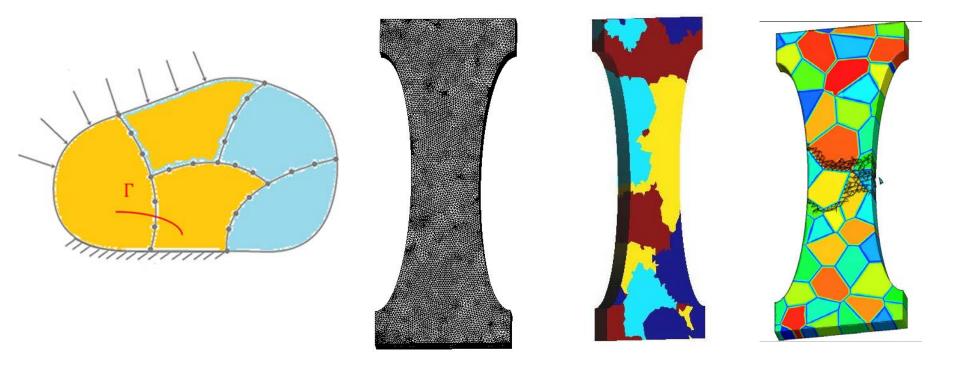
- Large scale FE numerical simulations
- Simplified procedure for a top-down approach with decoupled responses.
- Assessment of safety against accidental drop
- Simulation of fracture processes in polycrystals
- Applied to design of accelerometers and microphone



15

2.4 MEMS modelling – 3D Numerical modelling and simulation of fracture processes in polycrystals

Domain decomposition techniques applied to the 3D FE simulation of fracture processes in polycrystalline MEMS.

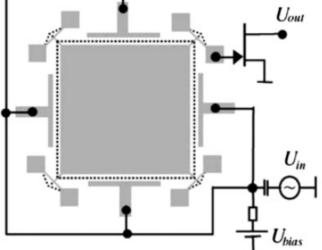


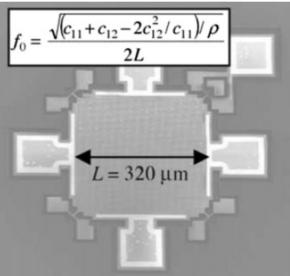


2.5 MEMS modelling –Numerical modelling and simulation of multi-physics problems in MEMS

17

Application of the POD Model Order Reduction technique to the simulation of electromechanical vibration of a MEMS plane resonator. Computing time reduced of 90%.



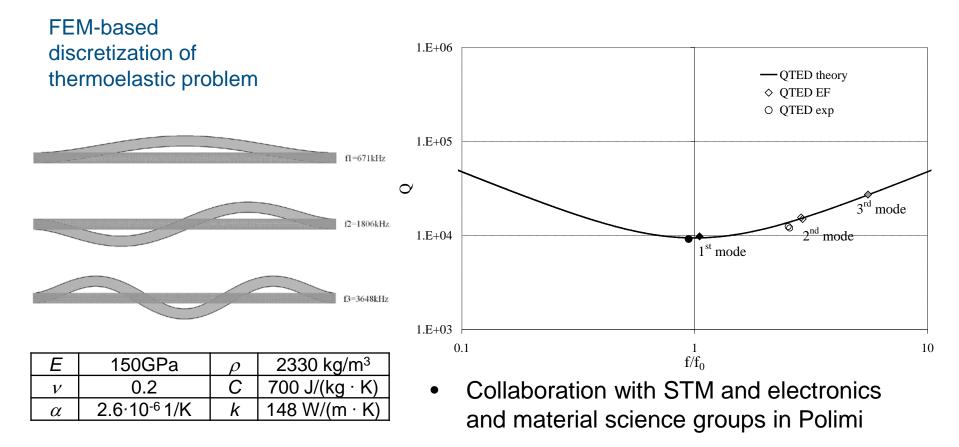


	Total time	error w.r.t. stag.	gain w.r.t. Stag. (%)	n° POM
S (t _{tot} =4·10 ⁻⁵)	24370	-	-	
S-POD (t _{snap} =3·10 ⁻⁷)	7121	8,32·10 ⁻²	-70,8	35
SD-POD (t _{snap} =3·10 ⁻⁷)	5587	7,02 ·10 ⁻²	-77,1	35
S-POD (t _{snap} =2·10 ⁻⁷)	4705	8,33·10 ⁻²	-80,7	38
SD-POD (t _{snap} =2·10 ⁻⁷)	3793	8,32·10 ⁻²	-84,4	38
S-POD (t _{snap} =1.5·10 ⁻⁷)	3639	7,25·10 ⁻²	-85,1	34
SD-POD (t _{snap} =1.5·10 ⁻⁷)	2826	5,86·10 ⁻²	-88,4	34
SD-POD updated	2664	9,98 10 ⁻²	-89,1	31

Alberto Corigliano - Micro Electro Mechanical Systems (MEMS)

3. Theoretical study and numerical modelling of damping (fluid, solid thermoelastic damping, anchor losses...)

Theoretical study and computational models for the correct evaluation of solid damping in MEMS. Possible applications to resonators, resonant accelerometers, gyroscopes, magnetometers...



Alberto Corigliano - Micro Electro Mechanical Systems (MEMS)

POLITECNICO DI MILANO

18

4. Resonators



Objective: to develop resonant devices which keep a very stable frequency in a wide range of temperatures, i.e. limited thermal drift.

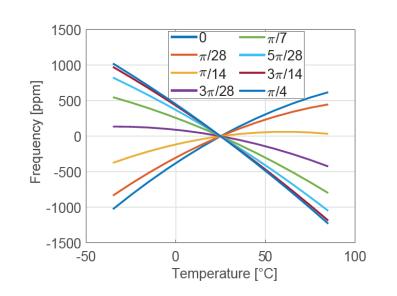
Main achievements:

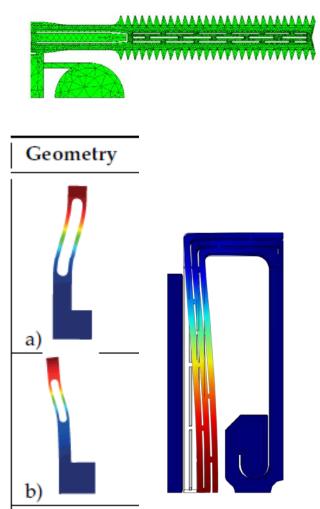
- 4.1 Modelling and simulation of resonators
- 4.2 In progress: experimental activity, design of new devices.

Collaboration with STM and electronics Polimi group

4. Resonators

- Modelling and simulation of damping
- Modelling and simulation of thermo-elastic response
- Shape optimization





Alberto Corigliano - Micro Electro Mechanical Systems (MEMS)



5. Micro-mirrors

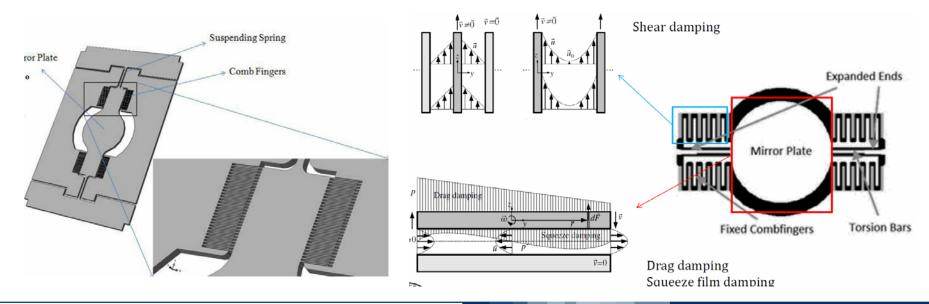
•Objective: to develop efficient micro-mirrors for video projection applications and solve damping and mechanical reliability issues

•Main achievements:

Fluid damping studies of torsional micro-mirrors Study and modelling of non-linear mechanical behaviour

Collaboration with STM

•EU funded project LAb4MEMS II: <u>http://www.lab4mems2.ite.waw.pl/</u>



Alberto Corigliano - Micro Electro Mechanical Systems (MEMS)

POLITECNICO DI MILANO

21

6. Micro-gyroscopes

- New gyroscope configurations
- AM, FM, LFM gyroscopes
- Modelling and simulation
- Collaboration with STM, electronics group and USA teams

Thermally

ctuation/Sensing Electrodes

> Piezoresistive Resonant

Study of piezoelectric gyroscopes

Lock-in-amplifie

Input (10 MΩ) 🕞

Electrostatic Actuation/Sensin Electrodes

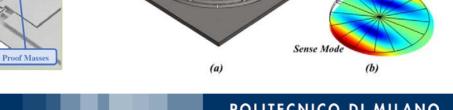
TH LOuton

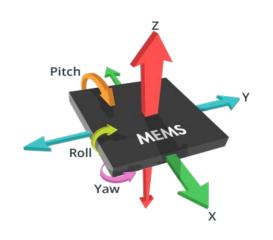
Support Beam

Internal Oscillator out (50 Ω)

Alberto Corigliano - Micro Electro Mechanical Systems (MEMS)

From IEEE MEMS 2015





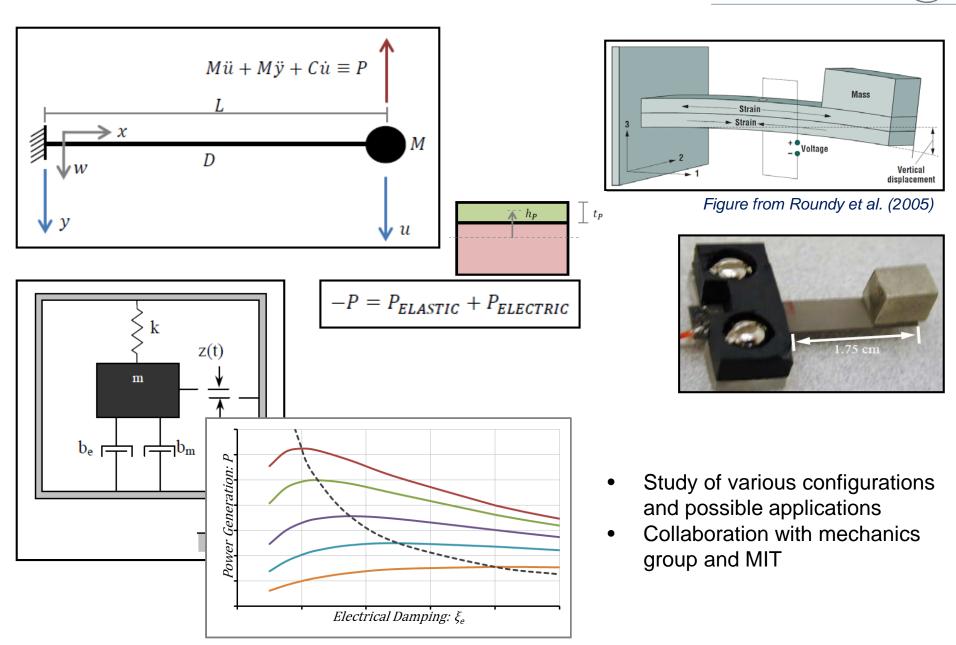
22



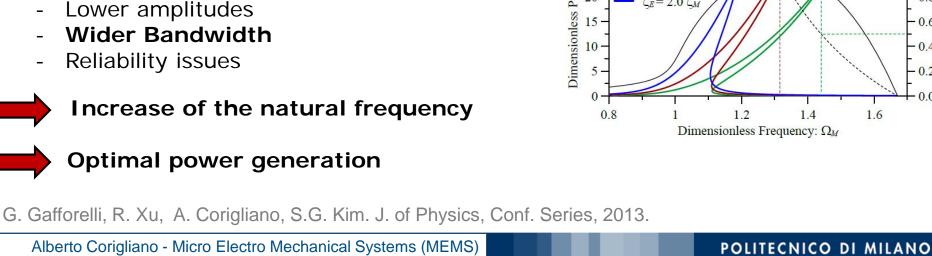
POLITECNICO DI MILANO

Drive Mode

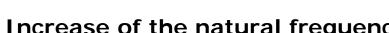
7. Piezoelectric energy harvesters

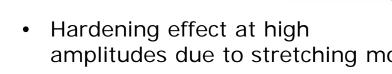






- Hardening effect at high amplitudes due to stretching mode
 - Smaller device
- High frequencies
- Lower amplitudes
- Wider Bandwidth
- Reliability issues



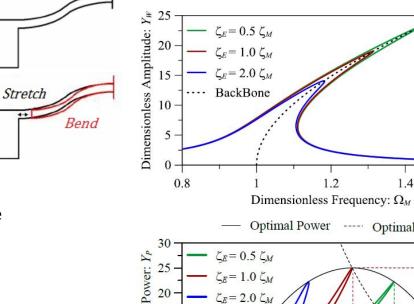


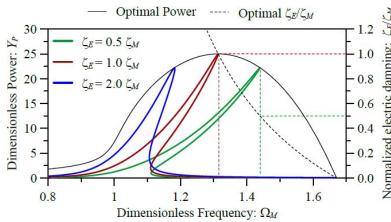
7. Ultra wide bandwidth Energy Harvester

Stretch

Bend

Nonlinear Resonance





24

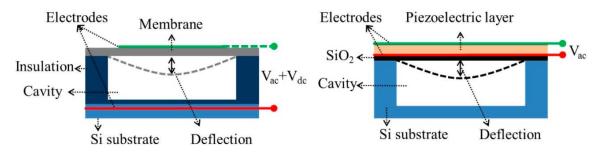


1.6

8. PMUT

Piezoelectric Micromachined Ultrasound Transducer (PMUT) for Integrated Sensing, Actuation and Imaging

- Collaboration with STM
- Study of piezo-actuated vibrating membranes
- Study of acoustice waves
- Study of multi-physics behaviour



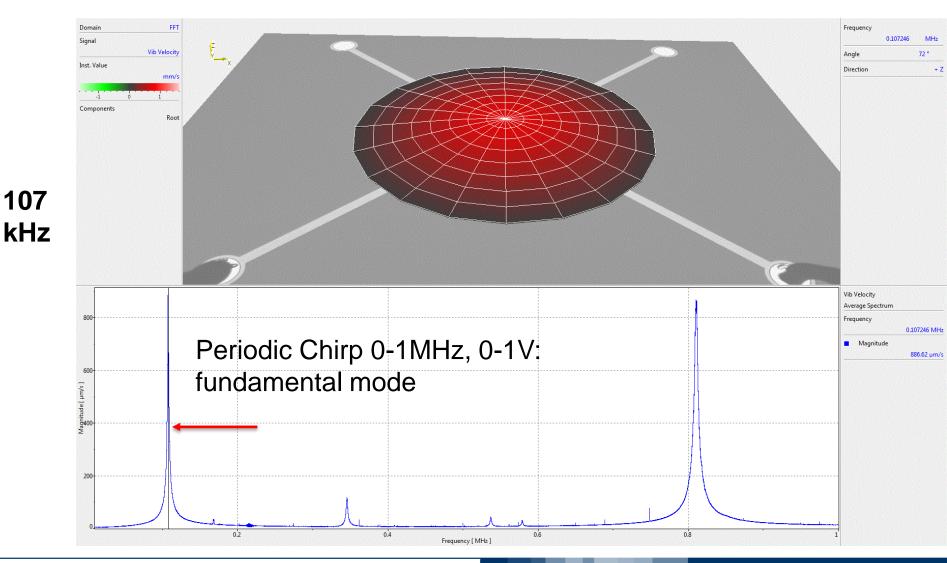
Sensors 2015, 15, 8020-8041; doi:10.3390/s150408020

Alberto Corigliano - Micro Electro Mechanical Systems (MEMS)

8. PMUT

26

Experimental modes Polytec MSA-500 Laser Doppler Vibrometer



Alberto Corigliano - Micro Electro Mechanical Systems (MEMS)

9. Technology related activities:

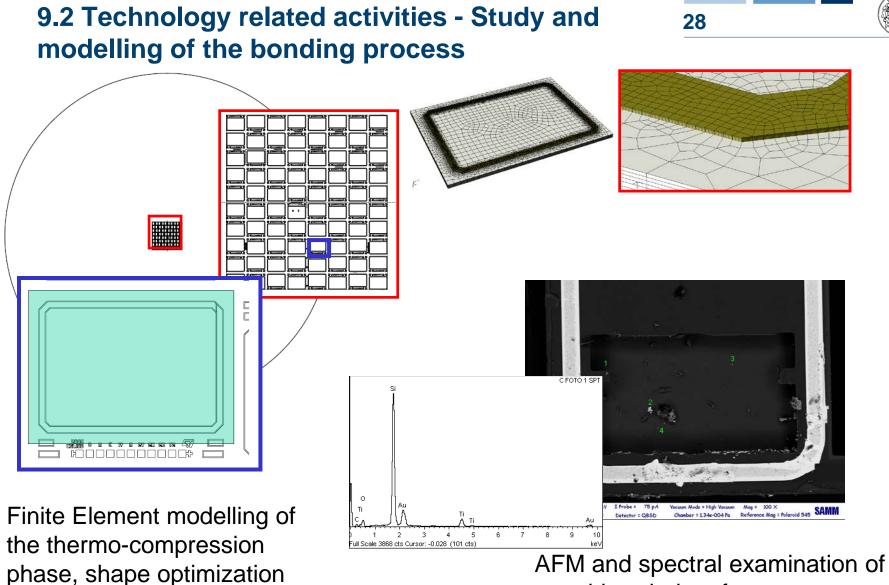


Objective: to help new technology development with dedicated simulation activity

Main expected achievements (new, in progress):

- 5.1 Study and modelling of the moulding process
- 5.2 Study and modelling of the wafer bonding process
- 5.3 Improvement of the etching process

• Collaboration with STM and material science groups



metal-bonded surfaces

10. Additive manufacturing applied to MEMS



In the framework of the inter-departmental lab MEMS&3D

Use of 3D and ink-jet printing for the fabrication of low-cost and 3D MEMS

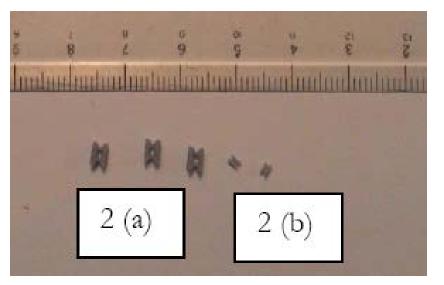
Possible collaboration with Physics Department for two-photon polymerization and fabrication of micro 3D devices

High resolution printing of 3D auxetic structures with different scales

Prototype designing



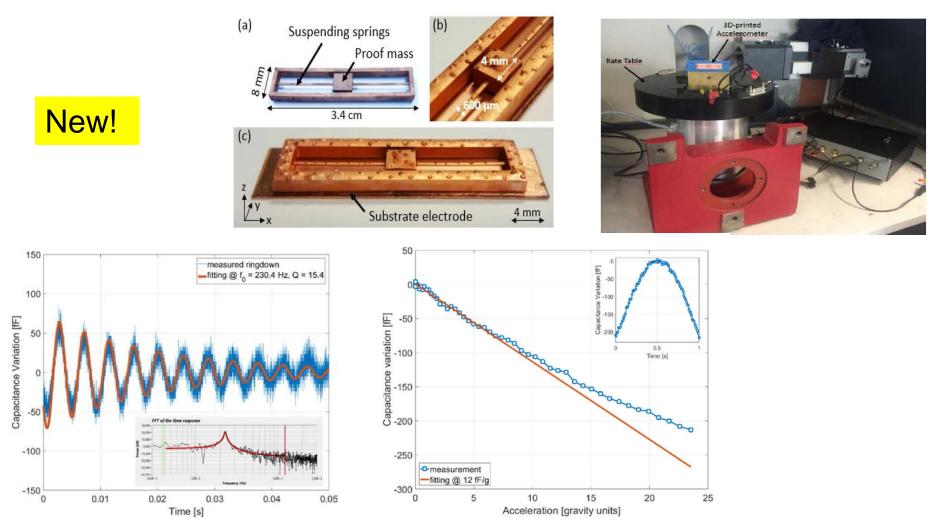
Prototype printing



SL printed 3D prototypes

10. Additive manufacturing applied to MEMS





Design, fabrication and testing of the first 3D-printed and wet metallized zaxis accelerometer

Eurosensors2017

C. Credi¹, V. Zega², G. Langfelder³, R. Bernasconi¹, A. Cigada⁴, <u>L. Magagnin^{1,*}</u>, M. Levi¹, A. Corigliano²

Alberto Corigliano - Micro Electro Mechanical Systems (MEMS)